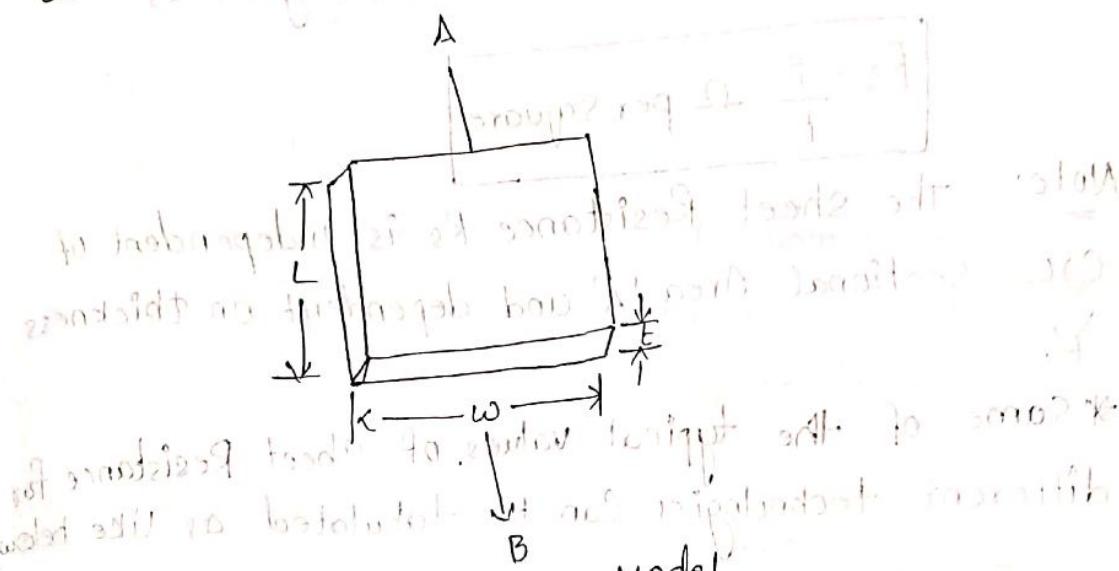


## UNIT-II

### Basic Circuit Concepts

#### Sheet Resistance ( $R_s$ )-

The concept of sheet resistance can be understood by considering a uniform slab material as shown in the figure below.



#### Sheet Resistance Model-

\* So from the given diagram we can say that it is having a length of ' $l$ ' and width of ' $w$ ' and with a thickness of ' $t$ '.

\* The resistance b/w the terminals A and B can be given as  $R_{AB}$ .

$$R_{AB} = \frac{P_l}{A}$$

where  $P$  - Resistivity

$l$  - length of the material

A - Cross-Sectional Area

\* for a uniform slab  $l=w$

$$\text{WKT } R_{AB} = \frac{P l}{A}$$

$$R_{AB} = \frac{P}{A}$$

$$R_{AB} = \frac{P}{w t}$$

$$= \frac{P}{w t} \quad (\text{uniform slab } l=w)$$

$$\boxed{R_{AB} = \frac{P}{t}}$$

$\therefore$  The sheet Resistance  $R_s$  can be given as

$$\boxed{R_s = \frac{P}{t} \Omega \text{ per square}}$$

Note:- The sheet Resistance  $R_s$  is independent of Cross-sectional Area ' $A$ ' and dependent on thickness ' $t$ '.

\* Some of the typical values of Sheet Resistance of different technologies can be tabulated as like below

| Layer                   | sheet Resistance     |                         |                     |
|-------------------------|----------------------|-------------------------|---------------------|
| Hilayer<br>bottom layer | 5 $\mu\text{m}$      | 2 $\mu\text{m}$ (orbit) | 1.2 $\mu\text{m}$   |
| Metal                   | 0.03                 | 0.04                    | 0.04                |
| Diffusion<br>(Active)   | 10 $\rightarrow$ 50  | 20 $\rightarrow$ 45     | 20 $\rightarrow$ 45 |
| silicid<br>side         | 2 $\rightarrow$ 4    | 11                      | 11                  |
| polysilicon             | 15 $\rightarrow$ 100 | 15 $\rightarrow$ 30     | 15 $\rightarrow$ 30 |
| N-transistor<br>channel | $10^4$               | $2 \times 10^4$         | $2 \times 10^4$     |
| P-transistor<br>channel | $2.5 \times 10^4$    | $4.5 \times 10^4$       | $4.5 \times 10^4$   |

Sheet Resistance Concept Applied to MOS transistors  
and inverters-  
The sheet resistance concept can be extended to inverters.

Here let us consider a CMOS inverter as shown below:

\* The channel resistance of PMOS can be given as

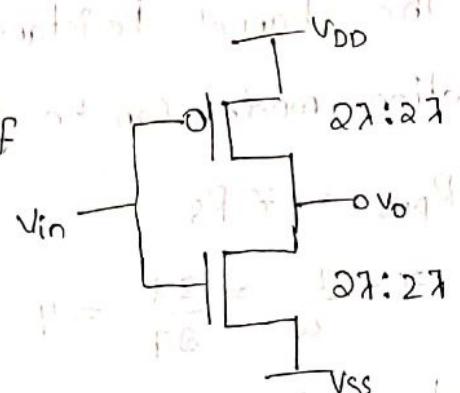
$$R_{PUS} = Z \cdot R_s$$

$$\text{WKT } Z = \frac{L}{w}$$

$$\Rightarrow \frac{\partial I}{\partial V} = 1$$

$$R_{PUS} = 1 \cdot R_s$$

$$= (2.5 \times 10^4)$$



R<sub>s</sub> values can be

taken for 5μm technology

for convenience.

\* The channel resistance of NMOS can be given as

$$R_{PDS} = Z \cdot R_s$$

$$Z = \frac{L}{w}$$

$$= \frac{\partial I}{\partial V} = 1$$

$$R_{PDS} = 1 \cdot R_s$$

$$= 1(10^4)$$

$$R_{PDS} = 10 \text{ k}\Omega$$

∴ The ON channel Resistance of CMOS inverter is

$$R_{ON} = R_{PUS} + R_{PDS}$$

$$= 25 \text{ k}\Omega + 10 \text{ k}\Omega$$

$$= 35 \text{ k}\Omega$$

# Sheet Resistance Concept Applied for NMOS Inverter

The NMOS inverter is diagrammatically as shown below.

The channel Resistance of depletion mode can be given as

$$R_{Pus} = Z \cdot R_s$$

$$Z = \frac{L}{W} = \frac{8\lambda}{2\lambda} = 4$$

The  $R_{Pus} = 4 \cdot R_s$

$$= 4 \cdot (2.5 \times 10^4)$$

$$= 40 \text{ k}\Omega$$

The channel Resistance of enhancement mode can be given as

$$R_{Pds} = Z \cdot R_s$$

$$Z = \frac{L}{W} = \frac{2\lambda}{2\lambda} = 1$$

$$R_{Pds} = 1 \cdot R_s$$

$$= 1(10^4)$$

$$= 10 \text{ k}\Omega$$

$\therefore$  The ON channel Resistance of NMOS inverter can be is  $R_{ON} = R_{Pus} + R_{Pds}$

$$= 40 \text{ k}\Omega + 10 \text{ k}\Omega$$

$$= 50 \text{ k}\Omega$$

the sheet Resistance Concept can be extended for transistors, for example consider two transistors as shown in figure 'a' and 'b' shown below.

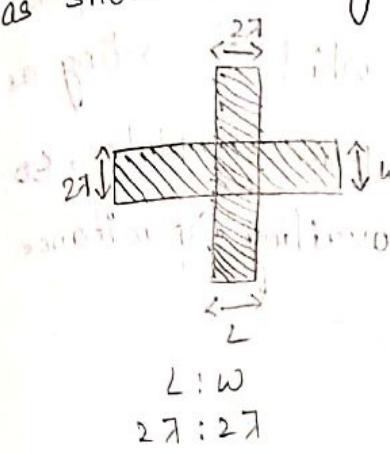


figure 'a'

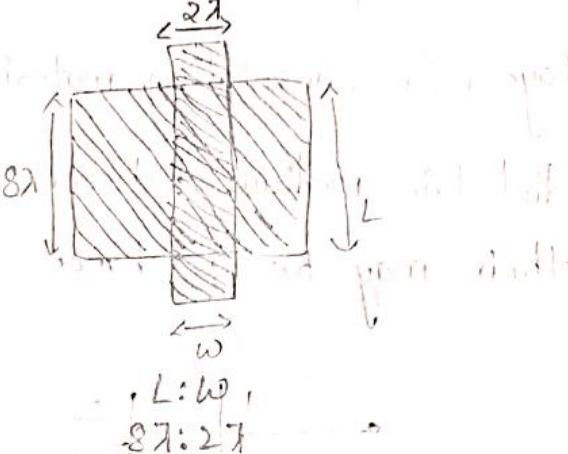


figure 'b'

In the above diagrams figure 'a' is having a length of '2l' and a width of '2l' and figure 'b' carries a length of '8l' with a width of '2l'.

for a fig 'a' the channel Resistance can be calculated as  $R = Z \cdot R_s$

$$\text{where } Z = \frac{L}{w} = \frac{2l}{2l} = 1$$

$$R = 1 \cdot R_s$$

$$R = 1 \cdot (10^4)$$

$$= 10 \text{ k}\Omega$$

the channel Resistance for fig 'b' can be calculated as  $R = Z \cdot R_s$

$$Z = \frac{L}{w} = \frac{8l}{2l} = 4$$

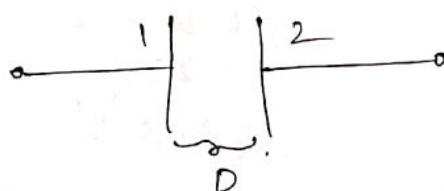
$$R = 4 \cdot R_s$$

$$= 4(10^4)$$

$$R = 40 \text{ k}\Omega$$

Area Capacitance of layers

In the IC fabrication process, the layers can be separated from one another by a oxide layer (i.e., insulating material) which is acting as dielectric medium between two parallel plates, so there may be a chance of availing capacitance.



The capacitance 'C' can be given as

$$C = \frac{\epsilon A}{D}$$

where  $\epsilon$  = permittivity and can be given as

$$\epsilon = \epsilon_0 \epsilon_{\text{ins}}$$

$\epsilon_0$  → Absolute permittivity = (or) permittivity of free space. ( $8.854 \times 10^{-12}$  farad./meter)

$\epsilon_{\text{ins}}$  → Relative permittivity = 4 for silicon

A = Area of plates

D = thickness of  $\text{SiO}_2$

\* Some of the typical values of Capacitance for 5μm, 2μm and 1.2μm technologies can be tabulated below.

| Capacitance                 | Value in $\text{PF} \times 10^4 / \mu\text{m}^2$ (relative values in brackets) |                |                  |
|-----------------------------|--|----------------|------------------|
|                             | $5\mu\text{m}$   | $2\mu\text{m}$ | $1.2\mu\text{m}$ |
| gate to channel capacitance | 4 (1.0)  | 8 (1.0)        | 16 (1.0)         |
| diffusion (active)          | 1 (0.25)   | 1.75 (0.25)    | 3.75 (0.25)      |
| polysilicon to substrate    | 0.4 (0.1)  | 0.6 (0.075)    | 0.6 (0.038)      |
| Metal 1 to substrate        | 0.3 (0.075)  | 0.33 (0.04)    | 0.33 (0.02)      |
| Metal 2 to Substrate        | 0.2 (0.5)  | 0.17 (0.02)    | 0.17 (0.01)      |
| Metal 2 to Metal 1          | 0.4 (0.1)  | 0.5 (0.06)     | 0.5 (0.03)       |
| Metal 2 to polysilicon      | 0.3 (0.075)  | 0.3 (0.038)    | 0.3 (0.018)      |

Standard unit of Capacitance ( $\square C_g$ ):-

The standard unit of Capacitance can be defined as gate to channel Capacitance of a MOS transistor having the feature size of  $L=W$ . Hence, for example, standard unit of Capacitance can be calculated for different technologies.

for  $5\mu\text{m}$  technology:-

$$\text{The area per standard square} = 5\mu\text{m} \times 5\mu\text{m} = 25\mu\text{m}^2$$

The standard unit of Capacitance ( $\square C_g$ ) can be given as

$$\square C_g = \text{Area/standard square} \times \text{Capacitance}$$

$$\Rightarrow 25 \mu\text{m}^2 \times 4 \times 10^{-4} \text{ PF}/\mu\text{m}^2$$

$$\Rightarrow 100 \times 10^{-4} \text{ PF}$$

$$\square C_g = 0.01 \text{ PF}$$

For 2.0μm technology

$$\text{Area/standard square} = 2.0\text{μm} \times 2.0\text{μm}$$
$$= 4\text{μm}^2$$

The standard unit Capacitance ( $\square C_g$ ) can be given as

$$\square C_g = \text{Area/standard Square} \times \text{Capacitance}$$

$$= 4 \times 10^{-2} \times 8 \times 10^{-4} \text{ PF}/\mu\text{m}^2 \cdot 0$$

$$= 32 \times 10^{-4} \text{ PF}$$

$$= 0.0032 \text{ PF}$$

for 1.2μm technology

$$\text{Area/standard Square} = 1.2\text{μm} \times 1.2\text{μm}$$

$$= 1.44 \text{μm}^2$$

The standard unit Capacitance ( $\square C_g$ ) can be given as

$$\square C_g = \text{Area/standard Square} \times \text{Capacitance}$$

$$= 1.44 \text{μm}^2 \times 16 \times 10^{-4} \text{ PF}/\mu\text{m}^2$$

$$= 23.04 \times 10^{-4} \text{ PF}$$

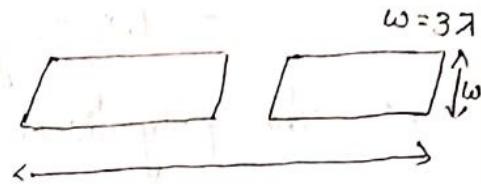
$$= 0.023 \text{ PF}$$

### Some Area Capacitance Calculations:

In this the relative values of Capacitance can be used for the representation of Capacitance and all values carried out in '2' based rules.

The relative Area can be represented as the ratio of Area of interest to the standard Area.

$$\therefore \text{Relative Area} = \frac{\text{Area of interest}}{\text{standard Area}}$$



$$\begin{aligned}\text{Relative Area} &= \frac{20\pi \times 32}{2\pi \times 27} \\ &= \frac{60\pi^2}{4\pi^2} = 15\end{aligned}$$

(\*) for 5um technology

(1) The Capacitance to substrate can be given as

$\Rightarrow$  Relative area  $\times$  Capacitance

$$= 15 \times 0.075 \text{ fCg}$$

$$= 1.125 \text{ fCg}$$

$\therefore$  The Capacitance to substrate is 1.125 fCg times of Square Cg (fCg).

(2) The diffusion Capacitance can be calculated

as = Relative area  $\times$  Capacitance

$$= 15 \times 0.25 \text{ fCg}$$

$$= 3.75 \text{ fCg}$$

$\therefore$  The diffusion capacitance is 3.75 times of fCg.

3) For polysilicon  
The capacitance for polysilicon can be calculated  
as = Relative Area × Capacitance.  
=  $15 \times 0.1 \text{ } \square \text{cg}$   
=  $1.5 \text{ } \square \text{cg}$

∴ The polysilicon Capacitance is 1.5 times of  $\square \text{cg}$

Delay unit ( $\gamma$ ):-

The delay unit ( $\gamma$ ) can be given as the product of Sheet Resistance ( $R_s$ ) and standard unit of gate Capacitance ( $\square \text{cg}$ ).

$$\boxed{\gamma = R_s \square \text{cg}}$$

for 5um technology

$$\text{WKT } \gamma = R_s \square \text{cg}$$

$$= 10^4 \times 0.01 \text{PF}$$

$$= 10^4 \times 0.01 \times 10^{-12}$$

$$= 100 \times 10^{-12}$$

$$= 1 \times 10^{-10}$$

$$\gamma = 0.1 \times 10^{-9}$$

$$\gamma = 0.1 \text{nsec}$$

for 2um technology

$$\text{WKT } \gamma = R_s \square \text{cg}$$

$$= 2 \times 10^4 \times 32 \times 10^{-4} \text{PF}$$

$$= 64 \text{PF}$$

$$\gamma = 64 \times 10^{15}$$

$$= 0.004 \times 10^{-9}$$

$$\gamma = 0.004 \text{ nsec}$$

for 1.2 um technology

$$\gamma = 8 \times 10^9$$

$$= 2 \times 10^9 \times 23.04 \times 10^9 \text{ pf}$$

$$= 46.08 \times 10^{12}$$

$$\gamma = 0.046 \text{ nsec}$$

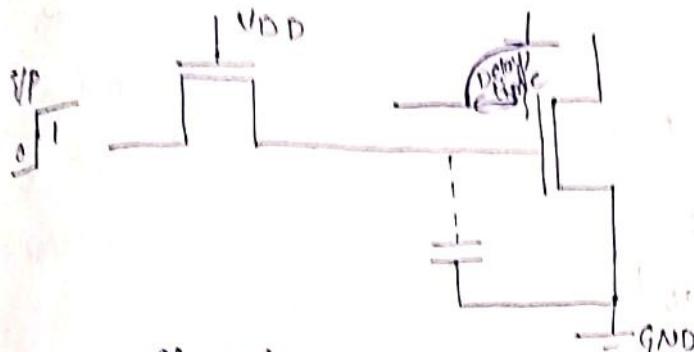


fig: Simple model to calculate delay time.

We know that the electron transit time  $\tau_{ds}$  as

$$\boxed{\tau_{ds} = \frac{L^2}{\mu v_{ds}}}$$

\* when ilp signal is transmitted through the pass transistors - the output voltage will get reduced to 63% of  $V_{DD}$  - that is  $0.63 \times V_{DD}$   
 $= 0.63 \times 5 \text{ V}$

\* for 5 um technology

$$\tau_{ds} = \frac{L^2}{\mu v_{ds}}$$

$$= \frac{5 \text{ um} \times 5 \text{ um}}{650 \text{ cm}^2/\text{V-sec} \times 3 \text{ V}}$$

$$= \frac{25 \times 10^{-6} \text{ sec}^2}{650 \times 0.01 \times 3 \times 10^3}$$

$$= \frac{25 \times 10^{-12}}{650 \times 0.01 \times 3} \text{ sec}$$

$$= \frac{25 \times 10^{-12}}{19.5}$$

$$= \frac{25 \times 10^{-3} \times 10^{-9}}{19.5}$$

$$= \frac{2.5 \times 10^{-9}}{19.5 \times 10^3}$$

$$= 0.128 \times 10^{-9}$$

$$\approx 0.13 \text{ nsec}$$

Note:- The delay unit  $\gamma$  is approximately equal to the electron transit time  $\tau_{ds}$ .

Inverter Delay :- Let us consider an nmos inverter with pullup resistor  $R_p$  and pulldown resistor  $R_d$ . Here let us consider an nmos inverter with a ratio of 4:1.

The pullup to pulldown ratio of nmos driven by another nmos is 4:1.

$$\text{i.e., } \frac{Z_{PU}}{Z_{PD}} = \frac{4}{1}$$

$$Z_{PU} = 4 Z_{PD}$$

$$Z_{PU} = 4 R_s$$

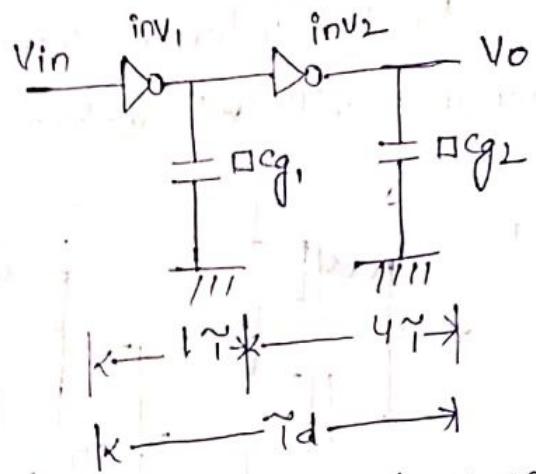
$$\frac{R_{PU}}{R_{PD}} = \frac{4}{1}$$

$$R_{PU} = 4 R_{PD}$$

$$R_{PU} = 4 R_S$$

$$R_{PU} = 4 \times 10^4$$

$$R_{PU} = 40 \text{ k}\Omega$$



\* the delay is not effected by the cascade connections of inverters but it is due to the turning on/off actions.

\* The total delay  $\gamma_d$  is the combination of both inverters.

$$\text{i.e., } \gamma_d = 1\gamma + 4\gamma$$

$$= \gamma [1+4]$$

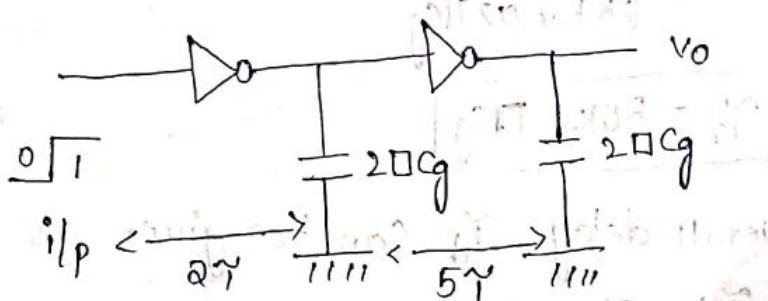
$$= \gamma \left[1 + \frac{4}{1}\right]$$

$$\gamma_d = \gamma \left[1 + \frac{Z_{PU}}{Z_{PD}}\right]$$

$\therefore$  The total delay for an NMOS inverter is  $\gamma_d = 5\gamma$ .

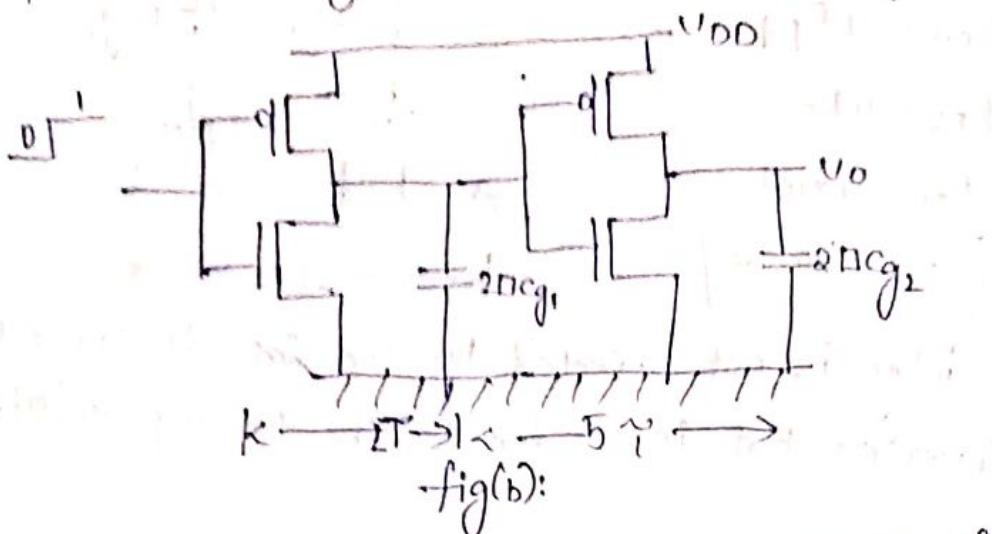
### CMOS Inverter Delay:-

Here let us consider an arrangement shown below for the calculation of CMOS inverter delay.



fig(a)

Due to the internal wiring Capacitance the load  
Capacitance will get doubled that is  $2\text{C}_g$ .



\* When D/p is  $V_{DD}$  (logic 1), then the nmos of inverter will get on and the capacitor will get discharge path through the nmos.

$$\text{i.e., } \tilde{\tau}_1 = R_n 2\text{nC}_g$$

$$\tilde{\tau}_1 = 20\text{k}\Omega \text{nC}_g$$

\* When the capacitor off inverter 1 is discharge then at the input of inverter 2 we have logic '0'. i.e., pmos of inverter 2 will get on and the capacitor will get charge.

$$\begin{aligned} \text{i.e., } \tilde{\tau}_2 &= R_p 2\text{nC}_g \\ &= (25\text{k}\Omega) \times 2\text{nC}_g \end{aligned}$$

$$\tilde{\tau}_2 = 50\text{k}\Omega \text{nC}_g$$

$\therefore$  The overall delay  $\tilde{\tau}_d$  can be given as

$$\begin{aligned} \tilde{\tau}_d &= \tilde{\tau}_1 + \tilde{\tau}_2 \\ &= 20\text{k}\Omega \text{nC}_g + 50\text{k}\Omega \text{nC}_g \end{aligned}$$

$$= 2R_s \square C_g + 5R_s \square C_g$$

$$= R_s \square C_g [2+5]$$

$$\tilde{T}_{dA} = 7 \tilde{T}$$

$\therefore$  The overall delay of CMOS inverter is  $\tilde{T}$ .

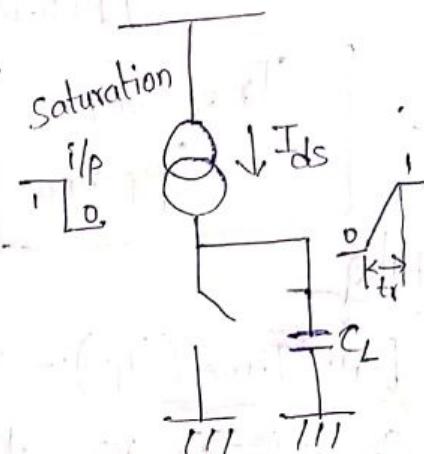
\* The overall delay can be better understood with a calculation of rise time ( $T_r$ ) and fall time ( $T_f$ ).

Rise time Calculation ( $T_r$ ):-

The calculation of rise time ' $T_r$ ' can be done when input is logic '0'.

wkT  $I_{ds}$  for saturation

$$I_{ds} = \frac{k\omega}{L} \left[ \frac{V_{gs} - V_t}{2} \right]^2$$



$$I_{ds} = \beta_p \left[ \frac{V_{gs} - V_{tp}}{2} \right]^2 \rightarrow (1)$$

$$V_{out} = I_{ds} R \rightarrow (2)$$

$$wkt \quad T_r = R C_L$$

$$R = \frac{T_r}{C_L} \rightarrow (3)$$

Sub (3) in (2)

$$V_{out} = I_{ds} \cdot \frac{T_r}{C_L}$$

$$\tilde{T}_r = \frac{V_{out} C_L}{I_{ds}}$$

$$= \frac{V_{out} C_L}{\beta_p [V_{gs} - V_{tp}]^2 / 2}$$

$$T_r = \frac{2 V_{out} C_L}{\beta P [V_{gs} - V_{tp}]^2}$$

$$V_{gs} = V_{DD}$$

$$V_{out} = V_{DD}$$

$$V_{tp} = 0.2 V_{DD}$$

$$T_r = \frac{2 \cdot V_{DD} C_L}{\beta P [V_{DD} - 0.2 V_{DD}]^2}$$

$$= \frac{2 V_{DD} C_L}{\beta P [0.64] V_{DD}^2}$$

$$\therefore T_r = \frac{2 C_L}{\beta P (0.64) V_{DD}}$$

$$\boxed{T_r \approx \frac{3 C_L}{\beta P V_{DD}}}$$

falling

Fall Time ( $T_f$ ):- The fall time ( $T_f$ ) can be calculated similarly to rise time ( $T_r$ ) calculation.

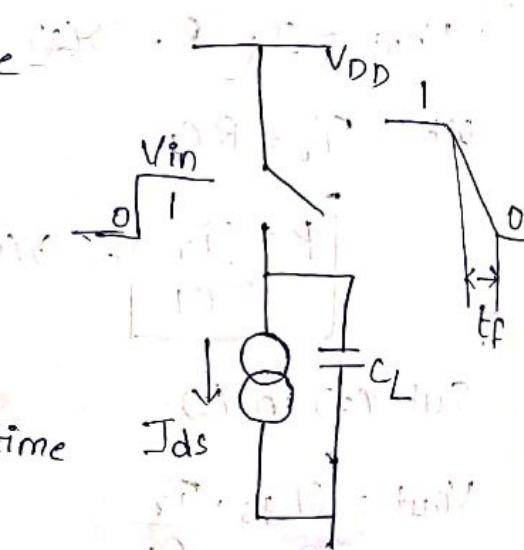
\* The fall time  $T_f$  can be given as

$$\boxed{T_f = \frac{3 C_L}{\beta n V_{DD}}}$$

(reference from rise time calculation)

\* The ratio of rise time to fall time can be given as

$$\frac{T_r}{T_f} = \frac{\frac{3 C_L}{\beta P / V_{DD}}}{\frac{3 C_L}{\beta n / V_{DD}}}$$



$$\frac{T_r}{T_f} = \frac{B_n}{B_p}$$

$$T_r \propto \frac{1}{B_p}$$

and fall time

$$T_f \propto \frac{1}{B_n}$$

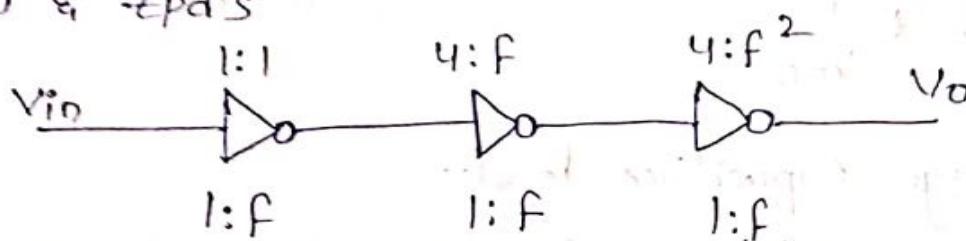
- \* The rise time ' $T_r$ ' and fall time ' $T_f$ ' both are  $\propto L$  and  $\propto \frac{1}{V_{DD}}$

### Driving Large Capacitive loads:-

- \* The concept of driving large capacitive loads may arise when the signals are propagating from on-chip to off-chip peripherals, which are having comparatively very large values.
- \* Here the load capacitance ' $C_L$ ' is equal orders  $>$  than the gate capacitance ' $C_g$ ' i.e.,  $C_L > 10^4 C_g$  [Assumption].
- \* In order to have decreased delay we need to maintain increased channel length which may further decrease the resistance.
- \* To drive large capacitive loads we are having 3 techniques.
  1. Cascaded Connections of inverters as drivers.
  2. Superbuffers as drivers.
  3. Bi-cmos drivers.

## 1. Cascaded Connections of Inverters & as drivers:-

- \* When driving large capacitive loads to have a minimum delay we should have low resistances.
- \* Low resistances can be obtained by having low Z<sub>PD</sub>'s & Z<sub>PD</sub>'s



- fig:- Cascaded inv as drivers
- \* The arrangement of Cascaded inverters as drivers is shown below.

- \* If we increase the width factor 'f' then the load on capacitance may increase that results in larger capacitive area.

- \* If there is increase in width factor then the resistance will get automatically decrease thereby we can have minimum delay.

for nmos:- Delay / stage =  $f\gamma$  for  $\Delta V_{in}$   
 $= 4f\gamma$  for  $\nabla V_{in}$

$$\tilde{T}_d = f\gamma + 4f\gamma = 5f\gamma$$

for cmos:- Delay / stage =  $2f\gamma$  for  $\Delta V_{in}$   
 $= 5f\gamma$  for  $\nabla V_{in}$

$$\tilde{T}_d = 2f\gamma + 5f\gamma = 7f\gamma$$

\* The relation b/w no. of inverters 'N' to width function 'f' can be given as

$$N^f = \frac{C_L}{C_g} = y$$

$$N^f = y$$

Apply 'log' on both sides

$$f \log N = y$$

\* If  $f = e$ ,  $e \log N = y$ .

$$N \log e = y$$

$$\boxed{N = y}$$

\* If  $N = \text{even}$ , then the delay is

$$\tilde{\tau} = \frac{N}{2} 5f\tilde{\tau} = 2.5f\tilde{\tau} \text{ for nmos}$$

$$\tilde{\tau} = \frac{N}{2} 7f\tilde{\tau} = 3.5f\tilde{\tau} \text{ for cmos}$$

\* If  $N = \text{odd}$ , then the delay is

$$\tilde{\tau} = [2.5(N-1) + 4]f\tilde{\tau} \text{ for nmos } \Delta V_{in}$$

$$\tilde{\tau} = [3.5(N-1) + 5]f\tilde{\tau} \text{ for cmos } \Delta V_{in}$$

$$\tilde{\tau} = [2.5(N-1) + 1]f\tilde{\tau} \text{ for nmos } \Delta V_{in}$$

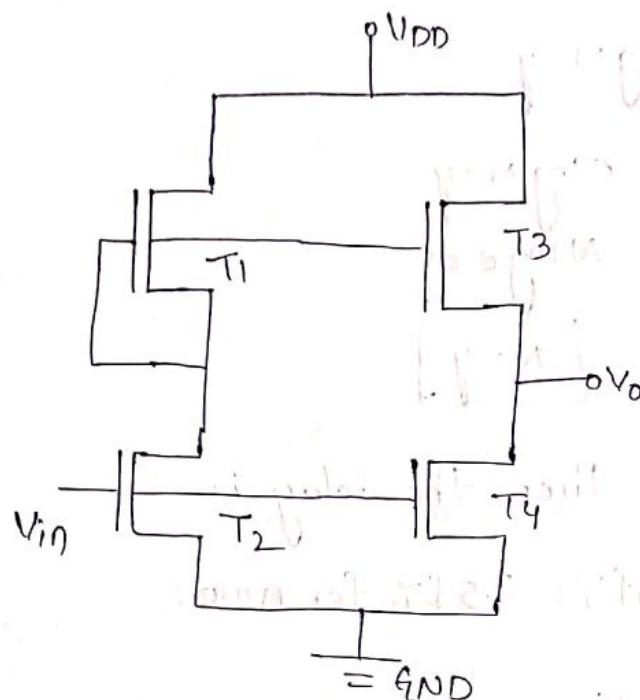
$$\tilde{\tau} = [3.5(N-1) + 2]f\tilde{\tau} \text{ for cmos } \Delta V_{in}$$

Note:- If there is increasing width factor 'f' then no. of transistors per chip will get reduced.

Q. Superbuffers as drivers:- It is classified into two types.

1. Inverting type super buffers
2. Non inverting type super buffers

1. Inverting type Superbuffers:



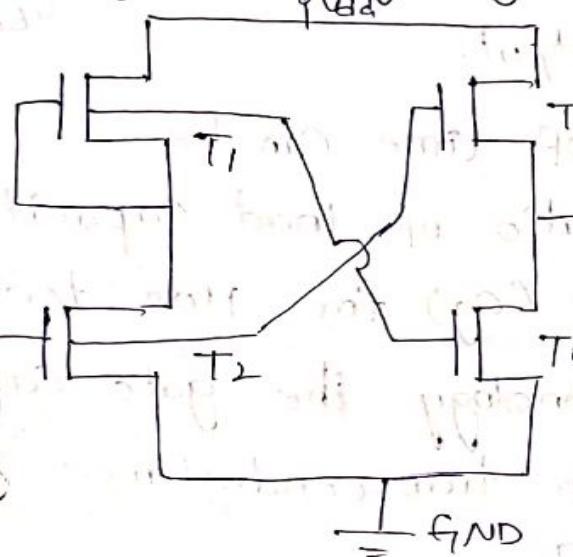
\* when  $V_{in}$  is logic '0' then the transistors  $T_2$  &  $T_4$  will get off and the transistors  $T_1$  &  $T_3$  will get on, thereby producing  $oV_o$  as logic '1'.

\* If  $V_{in}$  is logic '1' then the transistors  $T_1$  &  $T_3$  will get on and the transistors  $T_2$  &  $T_4$  will get on thereby producing  $oV_o$  as logic '0'.

Q. Non-inverting type Superbuffers:

\* when  $V_{in}$  is logic '0' then the transistors  $T_1$  &  $T_4$  will get on and the transistors  $T_2$  &  $T_3$  will get off thereby producing  $oV_o$  as logic '0'.

\* when  $V_{in}$  is logic '1' then the transistors  $T_2$  &  $T_3$  will get on and the transistors  $T_1$  &  $T_4$  will get off and thereby producing logic '1'.



8/1/19

### Bipolar Drivers :-

- In Bipolar technology, the output drive current is more for a given minimum silicon area.
- In this the transconductance  $g_m$  and low-current driving capabilities and current/area (or) more compared to MOS technology.

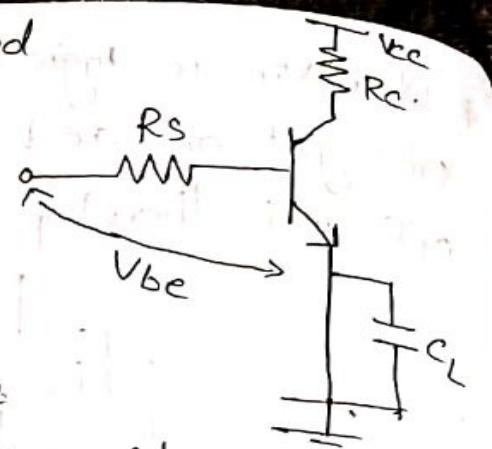
\* in this the current  $I_c$  is exponentially related to

the input voltage.

\* in this technology it is having the capability of driving large currents for the application of smaller voltages. and the current through the device depends on the base width  $w_b$  and the amount of doping level.

A simple representation that is use bipolar technology to change their states is shown below.

\* The amount of time required to change the input is equal to amount of time taken to change the output.



\* The amount of time can be given as the ratio of load capacitance ( $C_L$ ) to gate capacitance ( $C_g$ ) for MOS technology  $\Delta t = \frac{C_L}{C_g}$ .

\* In Bipolar technology the gate capacitance ( $C_g$ ) is replaced with transconductance ( $g_m$ ).

$$\Delta t = \frac{C_L}{g_m}$$

\* Therefore the total time taken can be represented as follows

$$T = T_{in} + \left( \frac{V}{I} \right) C_L \frac{1}{h_{fe}}$$

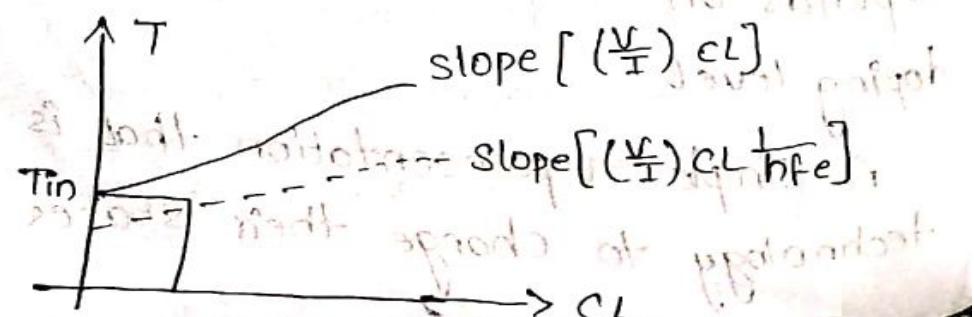
for bipolar

where  $T_{in}$  - the inbuilt time produced by device

To understand  $C_L$  - load capacitance

To understand  $h_{fe}$  - current amplification factor.

The graphical representation of MOS and Bipolar technology are drawn as below



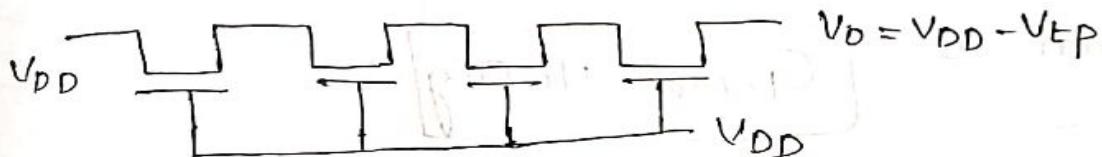
$$T = T_{in} + \left(\frac{V}{I}\right) CL \quad \text{for CMOS}$$

propagation delays:-

To transfer logic levels from one place to another place we are using series of pass transistors in b/w two points:-

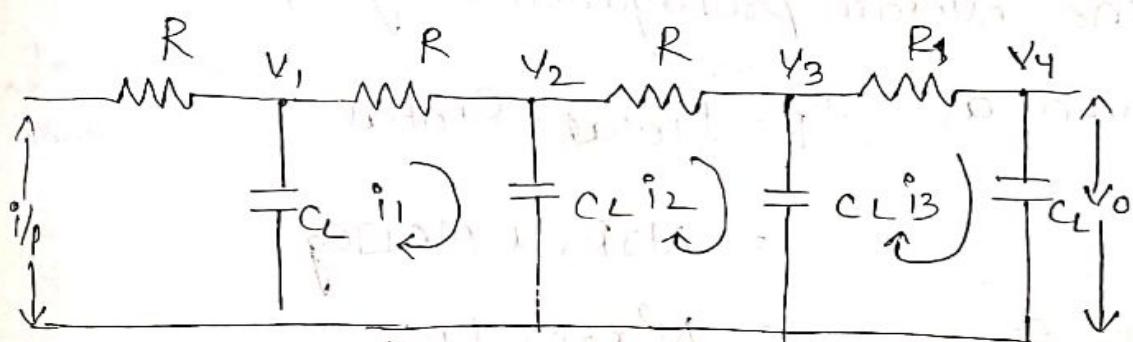
Hence in this case nmos pass transistors are used in series connection, the gate terminals are tight together and it is being given  $V_{DD}$ .

for example a series of four pass transistors are shown below.



Model for propagation delay

The equivalent circuit model can be drawn as



At node 2, we get write  $C \frac{dV_2}{dt} = i_1 - i_2$

$$C \frac{dV_2}{dt} = \frac{V_1 - V_2}{R} - \frac{V_2 - V_3}{R}$$

$$C \frac{dV_2}{dt} = \frac{V_1 - 2V_2 + V_3}{R}$$

$$RC \frac{dV_2}{dt} = V_1 - 2V_2 + V_3$$

$$Rc \frac{dv}{dt} = \frac{d^2v}{dx^2}$$

where  $x \Rightarrow$  distance

$\therefore$  the propagation delay  $t_p \propto x^2$

\* For 'N' no of networks the total resistance

can be given as  $R_{\text{total}} = N \times R_s$

where  $R_s$  = sheet Resistance

and  $\gamma = \text{relative Resistance}$

$N$  - no. of stages

\* For 'C' the total no of capacitance can be given as  $C_{\text{total}} = N C \square C_g$

Where  $C$  -

\* The overall propagation delay ' $t_p$ ' can be

given as  $t_p = R_{\text{total}} \times C_{\text{total}}$

$$= N \times R_s \times N C \square C_g$$

$$= N^2 \gamma R_s C \square C_g$$

$$= N^2 \gamma c R_s \square C_g$$

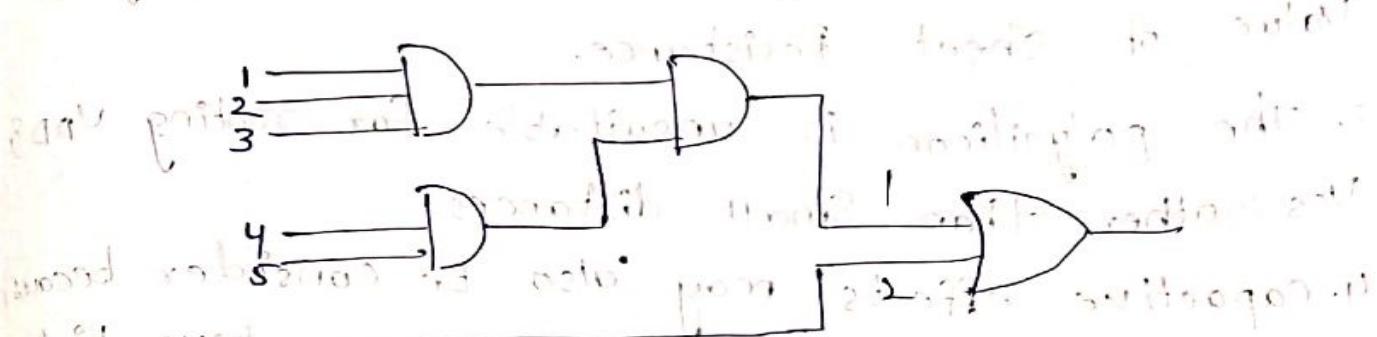
$$t_p = N^2 \gamma c \tau$$

$$\tau = R_s \square C_g$$

The propagation delay is  $\propto N^2$ .  
 If there is increase in  $N$ , it results in increased propagation delay.

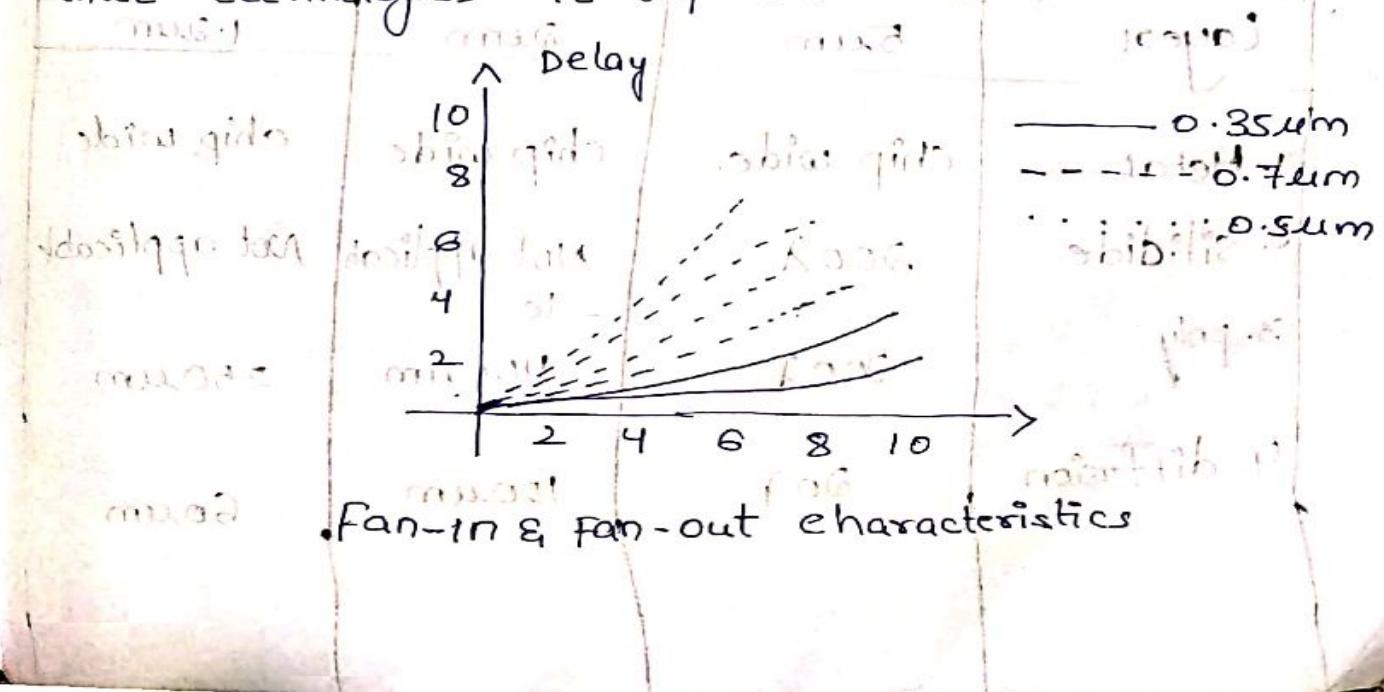
fan-in and fan-out characteristics:-  
 we have two major factors that influence operational speed of a gate terminal these are fan-in and fan-out.

fan-in :- The maximum no. of inputs that are applied to driven in gate is called fan-in.



fan-out :- The max no. of i/p's that are applied to driven gate is called fan-out.

\* The delay associated with fan-in & fan-out for three technologies is represented as



Choice of layers: In designing circuits for our convenience we have to consider several number of considerations which includes choice of layers.

1.  $V_{DD}$  and  $V_{SS}$  should be distributed on metal layer whenever possible.
2. The length of polysilicon should be used after careful consideration because of relatively high value of sheet resistance.
3. The polysilicon is unsuitable for routing  $V_{DD}$ ,  $V_{SS}$  other than small distances.
4. Capacitive effects may also be considered because the diffusion regions relatively may have high capacitive values to the substrate.

Table for electrical routes:-

| Layers       | Max length of wires |                |                |
|--------------|---------------------|----------------|----------------|
|              | 5μm                 | 2μm            | 1.2μm          |
| 1. Metal     | chip wide           | chip wide      | chip wide      |
| 2. Silicide  | 200λ                | Not applicable | Not applicable |
| 3. poly      | 200λ                | 400μm          | 250μm          |
| 4. diffusion | 200λ                | 100μm          | 60μm           |

## choice of layers:-

| layer                 | capacitance | Resistance | comment  |
|-----------------------|-------------|------------|--|
| 1. Metal              | Low         | Low        | * Good current capability without Large voltage drop and it is used for power distributions and global.                                    |
| 2. silicide           | Moderate    | Moderate   | * It has $Rc$ product has a moderate value, long wires are applicable; this layer is useful in place of poly silicon in some cases of nmos |
| 3. polysilicon        | Moderate    | High       | * It has $Rc$ product has IR moderate and high drop  |
| 4. diffusion (Active) | High        | Moderate   | * $Rc$ product is moderate and it has moderate IR drop hence it is hard to drive   |

minimum metal from top to bottom, platinum, standard to next to last or others

## Hiring Capacitance:-

We have Area Capacitance contributed in the calculation, pf, overall calculation capacitance.

The Area capacitances are associated with the layers to substrate and from gate to channel.

We have three other source for the calculation of overall capacitance.

1. Inter-layer capacitance

2. Peripheral (Junction) Capacitance

3. (fringing field) fringing fields capacitance

1. Inter-layer Capacitance:-

Parallel plate effects are present b/w one layer to another layer.

for example, for a given area metal to polysilicon capacitance is higher than metal to substrate capacitance.

2. peripheral Capacitance:-

The Source and drains of n-diffusion regions forms junctions with p-type substrate at uniform depth.

Similarly, p-active regions may form junctions with n-well (or) n type of substrate.

\* for diffusion regions each diode thus formed has associated with peripheral capacitance which is measured in PF/unit length.

- the typical values for different technologies given by

| diffusion<br>Capacitance   | Chemical Values                               |  |   |
|----------------------------|---|--|---|
|                            | 5 μm  | 2 μm   | 1.2 μm                                      |
| 1. $C_{\text{Area}}$       | $1.082 \times 10^{-4}$<br>PF/ $\mu\text{m}^2$ | $1.25 \times 10^{-4}$<br>PF/ $\mu\text{m}^2$ | $1.7 \times 10^{-4}$<br>PF/ $\mu\text{m}^2$ |
| 2. $C_{\text{peripheral}}$ | $8 \times 10^{-4}$<br>PF/ $\mu\text{m}^2$     | negligible                                   | negligible                                  |

### 3. fringing fields:-

capacitance due to fringing field effect can be a major component of overall capacitance of interconnected wires.

fringing field Capacitance can be of same order of area capacitance.

The capacitance of fringing field can be given as

$$C_{\text{ff}} = \epsilon_{\text{air}} \epsilon_0 l \left[ \frac{\pi}{\ln \left\{ 1 + \frac{2d}{t} \left( 1 + \sqrt{\frac{t}{d}} \right) \right\}} - \frac{t}{4d} \right]$$

where  $l$  = length of the wire

$t$  = thickness of the wire

\* The total wire capacitance can be given as

$$C_w = C_{\text{Area}} + C_{\text{ff}} \text{ (with small bridge)} \quad (1)$$

Wheeler's Correlation = Area of Capacitance.

$C_{ff}$  = fringing field Capacitance

### 3.2 Scaling of Mos ckt

Micro electronic technology can be characterised with the help of several indicators (or) figure of merits which includes

1. No of transistors per chip
2. minimum feature size
3. power dissipation
4. max operational frequency
5. die size
6. production cost

\* many of these fig of merits can be improved by reducing dimensions of transistors, interconnections and separation b/w features and by adjusting doping level and Supply voltage.

#### Scaling Models and Scaling factors:-

Basically we are having two Scaling models

1. Constant electric field scaling model
2. constant voltage scaling model

In accordance with these two Scaling models we are having a special scaling model which is the Combination of both Scaling models stated above and is called as Combined voltage and dimension Scaling model.

The following fig indicates that substrate doping level which are associated with Scaling of transistors.

- \* To scale any parameter we are using two scaling factors as  $\frac{1}{\alpha}$  &  $\frac{1}{\beta}$
- \*  $\frac{1}{\beta}$  is used for supply voltage levels ( $V_{DD}$ ) and for gate oxide thickness ( $D$ ) for all other linear dimensions we use  $\frac{1}{\alpha}$  as a scaling factor for both horizontal and vertical dimensions.

Note:- For Constant electric field Scaling model we use:  $\beta = \alpha$  and for Constant Voltage scaling model  $\beta = 1$

Scaling factors for device parameters:-

1. Gate area ( $A_g$ ):-  $A_g = L \times W$

'L' is the length of the channel which is scaled by  $\frac{1}{\alpha}$

and ' $\omega$ ' is the width of channel which is scaled by  $1/\alpha$

$$A_g = L \times \omega \\ = \frac{1}{\alpha} \times \frac{1}{d}$$

$$\boxed{A_g = \left(\frac{1}{\alpha^2}\right)}$$

2. Gate Capacitance per unit area ( $C_0$  or  $C_{ox}$ ) :-

$$C_x = \frac{\epsilon}{D}$$

where  $\epsilon$  = permittivity

$D$  = gate oxide thickness

$$C_x = \frac{\epsilon}{D} = \frac{\epsilon_0 \epsilon_{ins}}{D} = \frac{1}{V_B} = \beta$$

3. Gate Capacitance ( $C_g$ ) :-  $C_g = C_0 \omega L$

where  $C_0 \Rightarrow$  absolute capacitance and it is scaled by  $\beta$ .

$$C_g = C_0 \omega L = \beta \omega L = \beta \left(\frac{1}{\alpha}\right) \left(\frac{1}{d}\right)$$

$$= \frac{\beta}{\alpha^2}$$

4. parasite Capacitance ( $C_x$ ) :-

$$C_x = \frac{A_x}{d}$$

$A_x$  = Area,  $d$  = separation

$$C_x = \frac{1/\alpha^2}{1/\alpha} = 1/\alpha$$

5. Carrier density in the channel ( $Q_{on}$ ) :-

$$C = \frac{Q}{V}$$

$$C_0 V_{gs} = Q_{on}$$

$$Q_{ON} = \beta \cdot \frac{1}{\beta} = 1$$

6. channel on Resistance:-

$$R_{ON} = \frac{L}{\omega} = \frac{1/d}{\gamma/\alpha} = 1$$

7. gate delay ( $T_d$ ):-

$$\begin{aligned} T_d &= R_{ON} C_g \\ &= 1 \cdot \beta/d^2 \\ &= \beta/d^2 \end{aligned}$$

8. Maximum operating frequency ( $f_0$ ):-

$$\begin{aligned} f_0 &= \frac{\omega}{L} \frac{m_C V_{DD}}{C_g} = \frac{\beta \cdot \frac{1}{\beta}}{\frac{\beta/d^2}{d}} = \frac{1}{\beta/d^2} \\ &= \frac{\alpha^2}{\beta} \end{aligned}$$

9. Saturation Current ( $I_{DS}$ ):-

$$\begin{aligned} I_{DS} &= \frac{k\omega}{L} \frac{[V_{GS} - V_T]^2}{2} \\ &= 1 \left[ \frac{1}{\beta} - \frac{1}{\beta} \right]^2 \\ &= 1/\beta^2 \end{aligned}$$

$$I_{DS} = \frac{C_C \omega m}{L} \frac{[V_{GS} - V_T]^2}{2}$$

$$= \beta \cdot \frac{1}{\beta^2}$$

$$= 1/\beta$$

10. current density (J) :-

$$J = \frac{I_{ds}}{A} = \frac{1/\beta}{1/d^2}$$
$$= \alpha^2 / \beta$$

11. Switching energy per gate:-

$$E_g = \frac{1}{2} C_g V_{dd}^2$$
$$= \frac{1}{2} \frac{\beta}{\alpha^2} \cdot \frac{1}{\beta^2}$$
$$= \frac{1}{2\alpha^2\beta}$$

12. power dissipation per gate:-

$$P_g = P_{gs} + P_{gd} \quad P_{gs} = \frac{V_{dd}^2}{R_{on}}, \quad P_{gd} = E_g \cdot f_o$$

$$P_{gs} = \frac{1/\beta^2}{1} = 1/\beta^2 \quad ; \quad P_{gd} = 1/\beta^2$$

$$P_g = 2/\beta^2 = 1/\beta^2$$

13. power dissipation per unit area (PA) :-

$$PA = \frac{P_g}{\text{Area}} = \frac{1/\beta^2}{1/d^2}$$
$$= \alpha^2 / \beta^2$$

14. power speed product:-

$$P_t = P_g T_d = \frac{1/\beta^2}{1/d^2} \cdot \frac{\beta/\alpha^2}{1} \cdot \frac{1}{\alpha^2\beta}$$

## Scaling effects:-

| S.NO | Parameter                                   | Combined Voltage and dimension model | Constant electric field model<br>$B = \alpha$ | Constant Voltage Scaling model<br>$B = 1$ |
|------|---|--------------------------------------|---|---|
| 1.   | Supply voltage ( $V_{dd}$ )                 | $1/\beta$                            | $1/\alpha$                                    | 1   |
| 2.   | channel length ( $L$ )                      | $1/\alpha$                           | $1/\alpha$                                    | $1/\alpha$                                |
| 3.   | width of the channel ( $w$ )                | $1/\alpha$                           | $1/\alpha$                                    | $1/\alpha$                                |
| 4.   | gate oxide thickness ( $d$ )                | $1/\beta$                            | $1/\alpha$                                    | 1   |
| 5.   | gate area ( $A_g$ )                         | $1/\alpha^2$                         | $1/\alpha^2$                                  | $1/\alpha^2$                              |
| 6.   | gate capacitance per unit area ( $C_g$ )    | $\beta$                              | $\alpha$                                      | 1   |
| 7.   | gate capacitance ( $C_g$ )                  | $\beta/\alpha^2$                     | $\frac{\alpha}{\alpha^2} = \frac{1}{\alpha}$  | $1/\alpha^2$                              |
| 8.   | parastic Capacitance                        | $1/\alpha$                           | $1/\alpha$                                    | $1/\alpha$                                |
| 9.   | carrier density in the channel ( $Q_{on}$ ) | $1/\alpha$                           | $1/\alpha$                                    | $1/\alpha$                                |
| 10.  | channel on Resistance                       | 1                                    | 1   | 1   |
| 11.  | gate delay                                  | $\beta/\alpha^2$                     | $1/\alpha$                                    | $1/\alpha^2$                              |
| 12.  | maximum operating frequency                 | $\alpha^2/\beta$                     | $\alpha$                                      | $\alpha^2$                                |

|     |                                 |                           |                      |                      |
|-----|---------------------------------|---------------------------|----------------------|----------------------|
|     | Saturation Current              | $\frac{1}{\beta}$         |                      |                      |
| 14. | Current density                 | $\alpha^2/\beta$          | $\alpha$             | $\alpha^2$           |
| 15. | Switching energy per gate       | $\frac{1}{\alpha^2}\beta$ | $\frac{1}{\alpha^3}$ | $\frac{1}{\alpha^2}$ |
| 16. | Power dissipation per gate      | $\frac{1}{\beta^2}$       | $\frac{1}{\alpha^2}$ | 1                    |
| 17. | power dissipation per unit area | $\alpha^2/\beta^2$        | 1                    | $\alpha^2$           |
| 18. | Power speed product             | $\frac{1}{\alpha^2}\beta$ | $\frac{1}{\alpha^3}$ | $\frac{1}{\alpha^2}$ |

\*Limitations of Scaling:—

Substrate Doping:—

So far, we have discussed about various effects, we have neglected built in (junction) potential  $V_B$  which in turn depends on substrate doping level and this is acceptable so long as  $V_B$  is smaller compared to  $V_{DD}$ .

Substrate doping Scaling factors:—

As the length of the channel of a mos transistor is reduce, that depletion region width also to be scaled down to prevent source and drain depletions regions from meeting.

The depletion width 'd' for the junction can be given as

$$d = \sqrt{\frac{2\epsilon_0\epsilon_{ins} V_B}{Q/N_B}}$$

where  $q = \text{charge}$

$\epsilon_0$  = permittivity of free space

$\epsilon_{\text{ins}}$  = permittivity of material

$V_B = V_b$  built-in potential

The inbuilt potential  $V_B$  can be given as

$$V_B = \frac{kT}{q} \ln \left( \frac{N_D N_B}{n_i^2} \right)$$

where  $N_D$  = drain (or) source doping level

$n_i$  = intrinsic carrier concentration

\* If we increase  $N_B$  to reduce  $d$ , at the same time  $V_B$  is also increased.

\* For combined voltage & dimension model the total applied voltage can be given as

$$V_a = m V_B$$

where  $m$  is a real number

then  $V = V_a + V_B$

$$V = m V_B + V_B$$

$$V = V_B (m+1)$$

Now if is scale down  $V_a$  then the voltage can be given as

$$V_a = \frac{m V_B}{B}$$

$$V = \frac{m V_B}{B} + V_B$$

$$V = \frac{mV_B + \beta V_B}{\beta}$$

$$V_2 = \frac{V_B(m+\beta)}{\beta}$$

$\therefore$  The effective scale voltage can be given as

$$\begin{aligned} V_S &= \frac{V_2}{V_1} \\ &= \frac{V_B(m+\beta)}{V_B(m+1)} \end{aligned}$$

$$V_S = \frac{(m+\beta)}{\beta(m+1)}$$

Limitations due to Sub threshold Currents ( $I_{sub}$ ):-  
one of the major concern in the scaling of devices is the effect of Sub threshold current  $I_{sub}$  which can be given as

$$I_{sub} \propto e^{\frac{(V_{gs}-V_t)}{KT/q}}$$

When a transistor is in off state, the value of  $V_{gs}-V_t$  is negative and it should be as large as possible to minimize  $I_{sub}$ .

As the voltages are scaled down then the ratio of  $V_{gs}-V_t$  to  $KT/q$  will decrease so that sub-threshold current increases.

\* for this reason, it may be desirable to scale both vgs & vt by a factor  $1/b > 1/a$ . Since 'a' is generally greater than 'b'.

\* The maximum electric field across the depletion region can be given as

$$E_{max} = \frac{2V}{d} = \frac{2(V_a - V_b)}{d}$$

\* The junction breakdown voltage can be given as

$$BV = \frac{E_0 \epsilon_{Si} E^2}{2qNB}$$

Note:- Extra care is therefore required in estimating the breakdown voltages for scaled devices.

\* The electric field are greater and breakdown voltage is greater at the corner of diffusion regions underlying  $SiO_2$ .

### Limitations on logic levels and Supply voltages due to noise :-

The major advantages in scaling of devices are smaller gate delay time i.e., higher operating frequency and lower internal power consumption.

\* The lowering of interface spacing and higher switching increase noise in VLSI chips. So noise may also be amplified and is thus a major concern.

\* The mean square current fluxations in the channel can be given as

$$I^2 = 4kT R_n g_m A_f \rightarrow (1)$$

where  $R_n$  = noise Resistance

$A_f$  = Band width

$g_m = B V_p$

$V_p$  = pinch off Voltage

The equivalent Resistance  $R_n$  can be given as

$$R_n = \frac{\left( \frac{1}{2} \frac{V_g}{V_p} + \frac{1}{6} \right)}{g_m} \rightarrow (2)$$

where  $V_g' = V_{GS} - V_T + V_B$

$$V_p' = V_p + V_B$$

Similarly the thermal equivalent ' $R_n g_m'$ ' can be given as

$$R_n g_m = \frac{1}{2} \frac{(V_{GS} - V_T + V_B)}{(V_p + V_B)} + \frac{1}{6} \rightarrow (3)$$

Observing eqn(3) the value ' $R_n g_m'$ ' is also dependent on  $V_g$  but very small extent.

The modified expression for  $R_n g_m$  when  $t_{ox}$  is scaled as

$$R_n g_m = \frac{1}{2} \left[ \frac{V_g}{V_g - \frac{1}{2} \left( \frac{a}{C_{ox}} \right)^2 (1 + 4g'_{COX})^{1/2} - 1} \right] + \frac{1}{6}$$

\* If there is an increase in the value of  $C_{ox}$  then  $R_{ngm}$  decreases by a small amount which in turn decrease the ratio of logic levels to thermal noise by same amount.

29/11/19

### Switch logic:-

Switch logic is based on pass transistors (or) on the transmission gates.

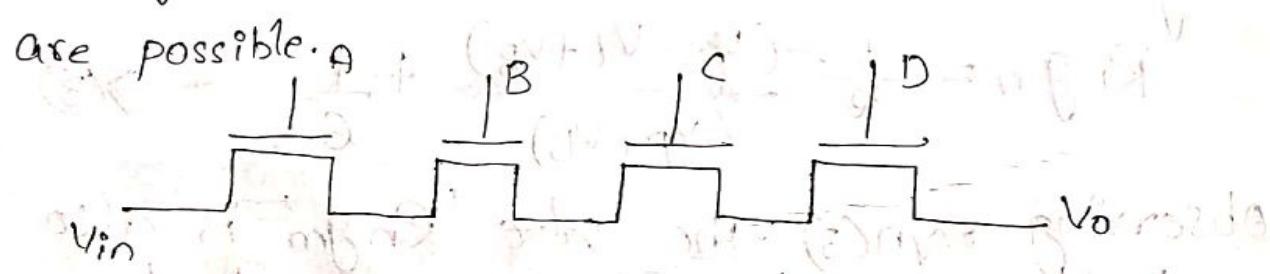
\* This approach is fast for small arrays and takes no static current from supply rails.

\* Hence power dissipation such arrays is small.

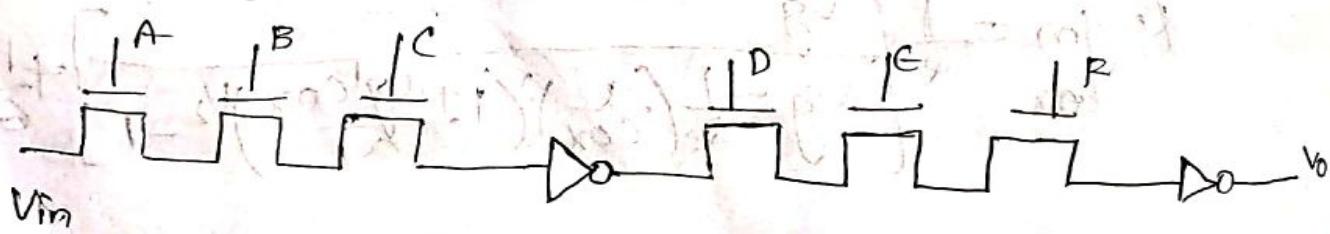
∴ Current flow only on switching.

\* Pass transistor logic is similar to logic arrays based on delayed contacts.

\* The basic AND connections are set out as shown in fig below but many combinations of switches are possible.

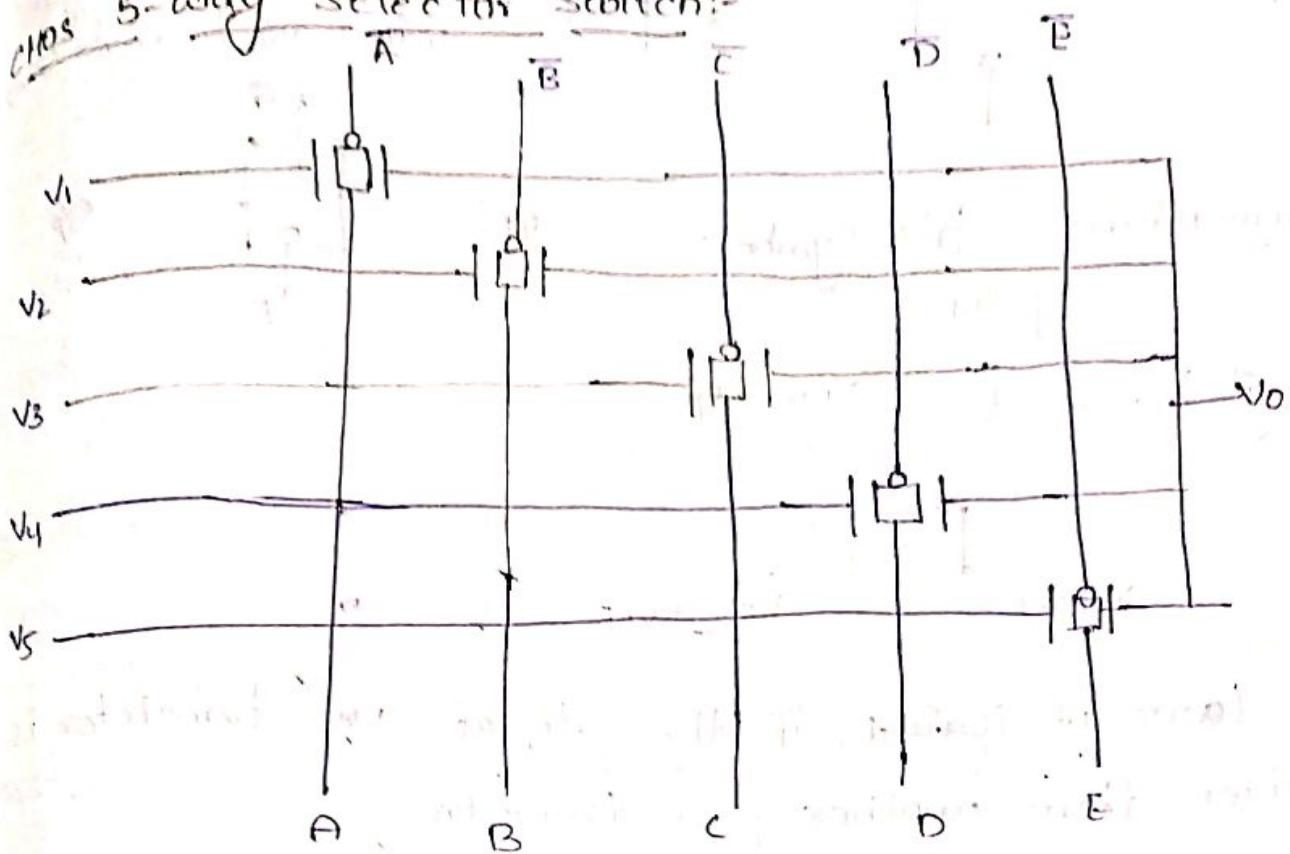


Here  $V_0$  logic levels will be degraded by  $V_t$  effects.



$$V_0 = V_{in} \text{ when } ABCDEF = 1$$

## CLOS 5-way Selector Switch:-

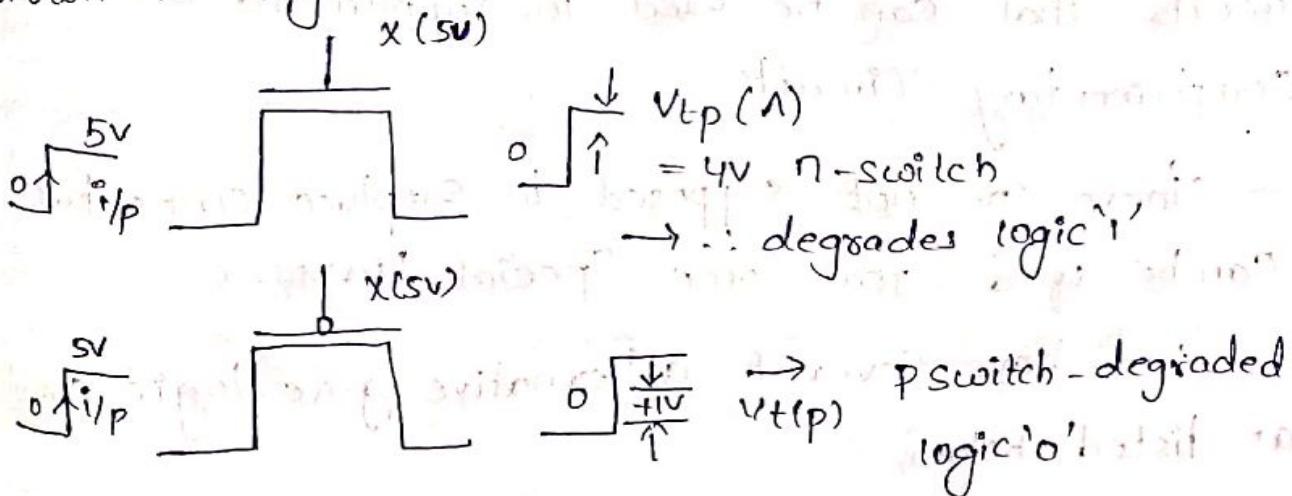


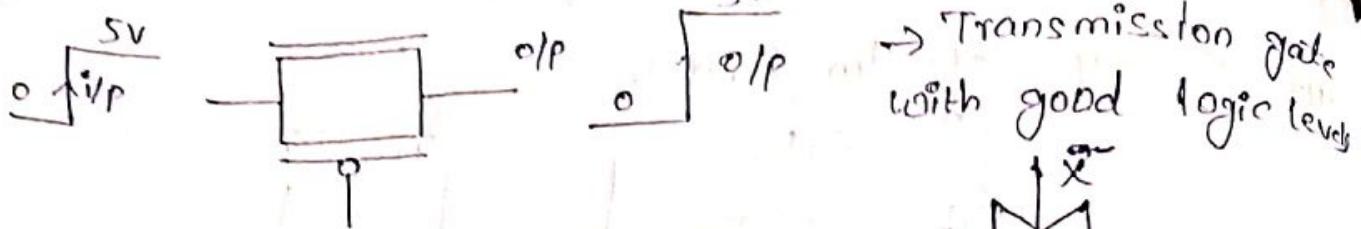
$$V_0 = V_1 A + V_2 B + V_3 C + V_4 D + V_5 E$$

Assuming A, B, C, D, E are mutually exclusive i.e., V<sub>out</sub> logic levels are not degraded by 'V<sub>T</sub>' effect.

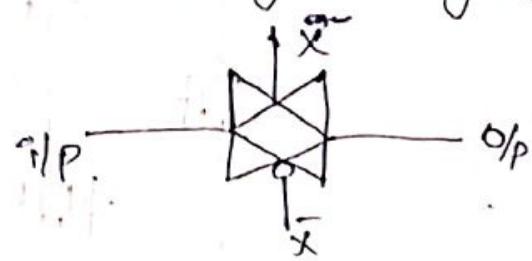
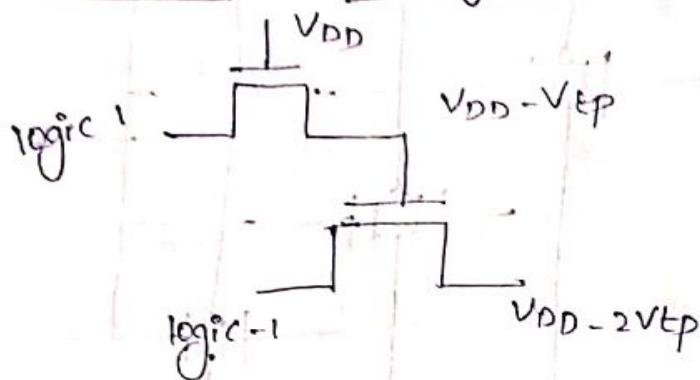
## Pass transistor and Transmission gates:-

~~Switches and switch logics may be form from~~  
Switches and switch logics may be formed from simple 'n' (or) p-type pass transistors in parallel as shown in figure below.





Transmission gate symbol:-



Laws of logic-1, if the gate of pass transistor is driven from another pass transistor.

fig:- Some properties of pass transistors and some logic families.

Alternative Gate Circuits (or) Gate logic:-

CMOS circuits suffer from increased area and Corresponding increasing capacitance and delays logic gates becomes more complicate.

for this Reason, the designers develops the circuits that can be used to supplement the complimentary circuits.

There are not supposed to replace CMOS, but can be used for some special purposes.

We have several alternative gate logic circuits as listed below,

(1) pseudo nmos

(2) Dynamic

(3) c<sup>2</sup>mos (clocked cmos)

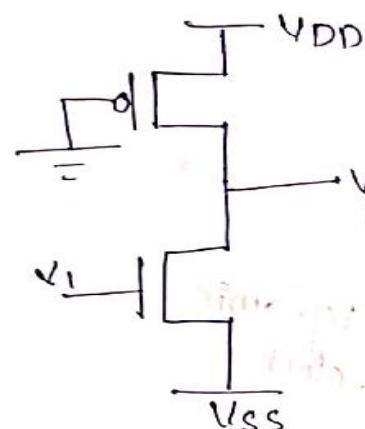
(4) domino logic

(5) np cmos logic

pseudo nmos logic:-

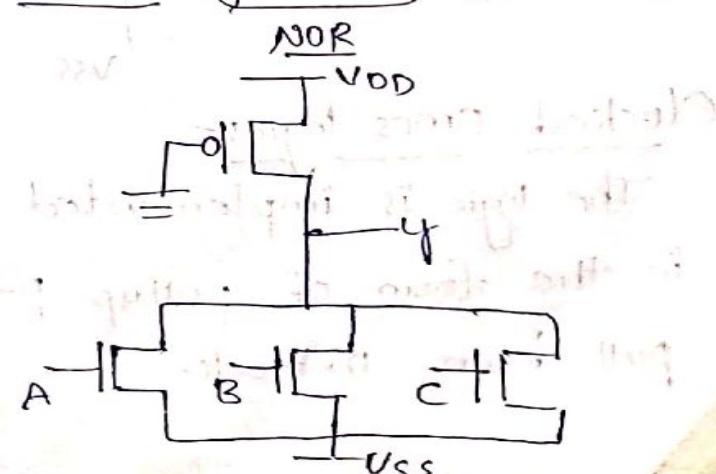
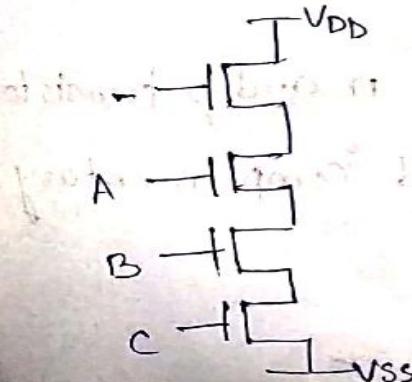
The pseudo nmos logic is one of the type of alternative gate circuits i.e., used to supplement for mos circuits.

In this pseudo nmos circuit the depletion mode pull up mos transistor is replaced with p-mos transistor whose gate terminal is always ground.



Implementation of 3 Input. nAND gate & NOR gates

Implementation of three i/p NOR gate and nand gate using pseudo nmos logic:-

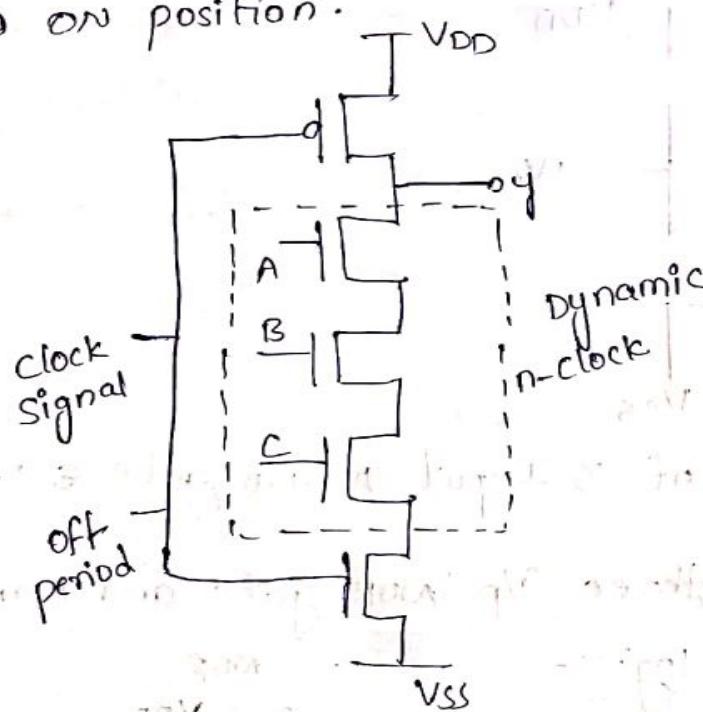


Note:- For 'n' numbers of i/p pseudo nmos logic requires 'n+1' numbers of transistors cmos logic require '2n' number of transistor.

### Dynamic Cmos logic

The actual logic is implemented in the n-block an p transistor is used for non-time critical pre-charging output. i.e. The output capacitance is charged to VDD during off period of clock signal ( $\phi$ ).

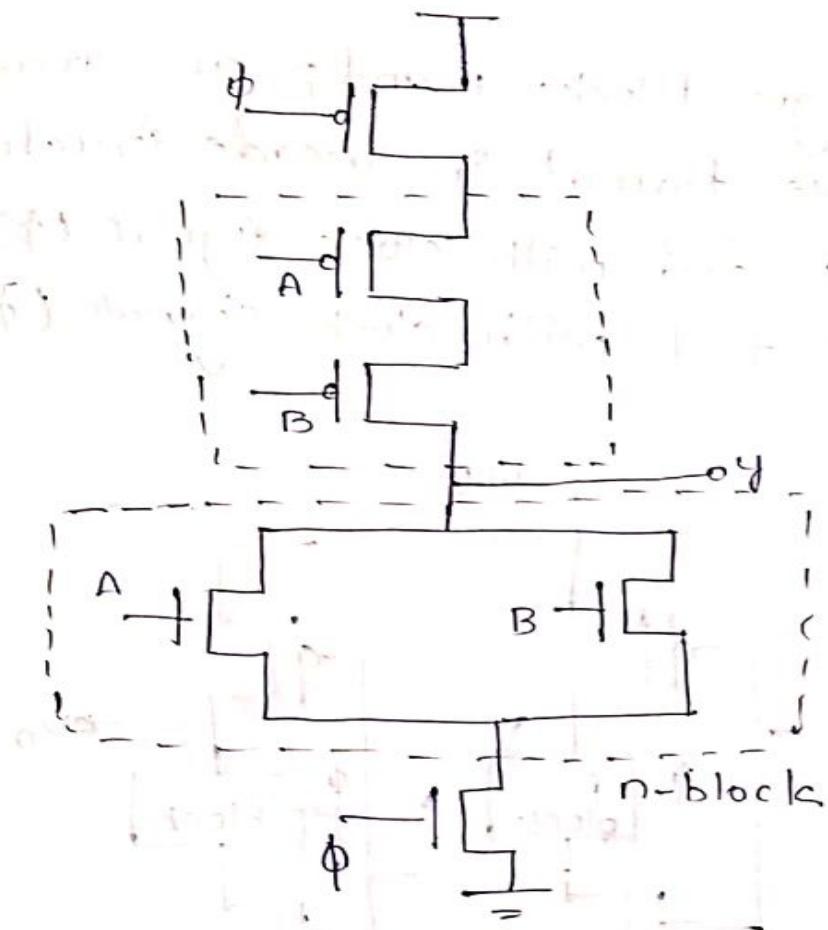
During this time, inputs due applied to n-block and state of logic is then evaluated during on period of clock when the bottom n-transistor is in on position.



### Clocked CMOS logic

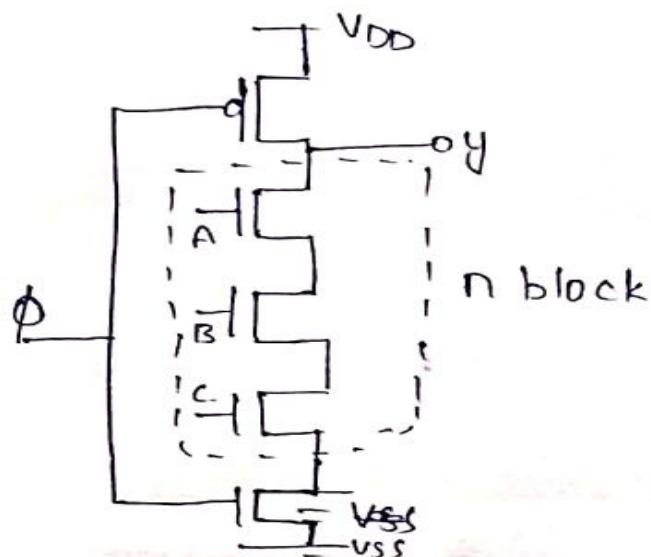
The logic is implemented in both n and p transistors in the form of pullup p-block and complimentary pull down n-block.

The logic in this can is evaluated only during the ON period of clock.



### Domino cmos logic:-

An extension of dynamic CMOS logic is called domino CMOS logic. This is an modified arrangement that allows cascading of logic structures using only a single phase clock. So, at the output we use a buffer.

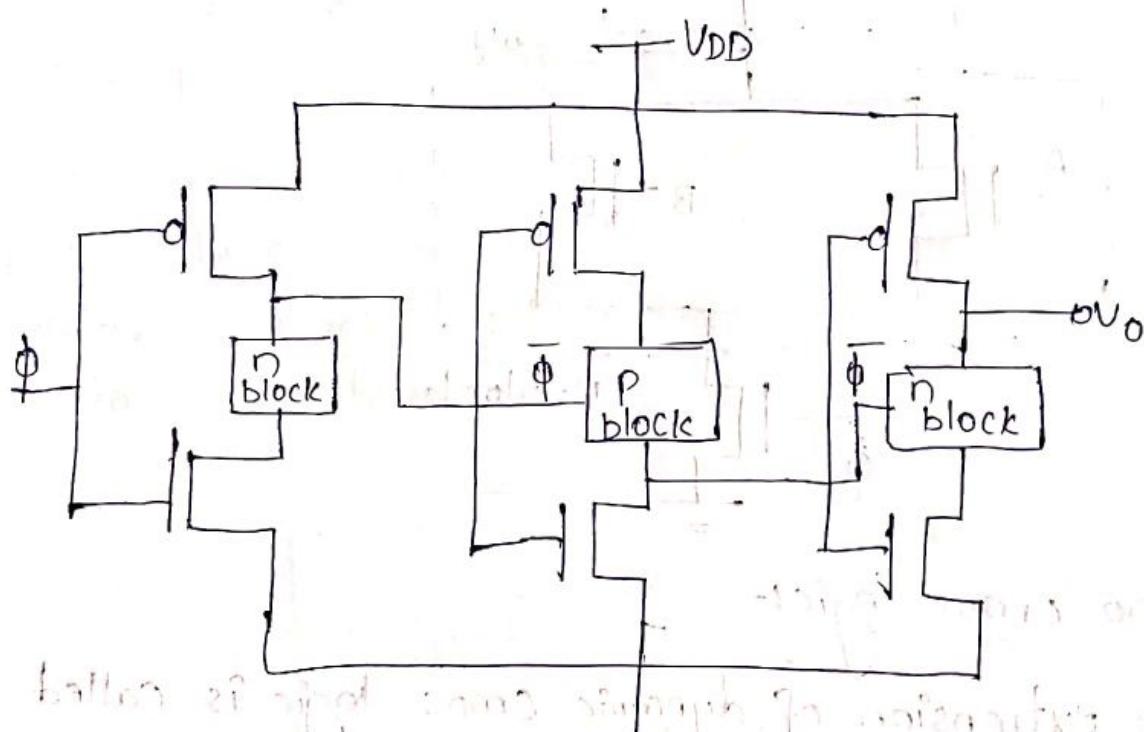


NP CMOS logic: This is another version of basic dynamic logic.

Circuit,

the actual logic blocks n and p are arranged in the alternative format in cascade structure.

one block is fed with clock signal ( $\phi$ ) and another block is fed with clock signal ( $\bar{\phi}$ ).



bottom right: same sample for n-channel after changing the bidirectional  $\leftrightarrow$  diff. signal comes with the p-channel individual signal to maintain switch but p need very higher voltage so it's mostly used in pmos